

Docket Number: 10981988-3
Application No. 10/643,264
Amendment B

Amendments to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

1. (currently amended) A method of making a part of a droplet plate, which part mounts to a substrate that carries a heat transducer and defines both a firing chamber to surround the transducer and a nozzle through which liquid in the chamber may pass from the chamber; the method comprising the steps of:

forming the part from a single type of dielectric material by depositing a first layer of the dielectric material using plasma-enhanced chemical vapor deposition;

shaping the firing chamber in the first layer;

depositing a second layer of the single type of dielectric material; and

making the nozzle in the second layer.

2. (canceled).

3. (currently amended) A method of making a part of a droplet plate, which part mounts to a substrate that carries a heat transducer and defines both a firing chamber to surround the transducer and a nozzle through which liquid in the chamber may pass from the chamber; the method comprising the steps of:

forming the part from a single type of dielectric material by depositing a first layer of the dielectric material;

shaping the firing chamber in the first layer;

depositing a second layer of the single type of dielectric material;

The method of claim 1 wherein the first layer and second layer of dielectric material are selected from the group consisting of silicon dioxide, silicon nitride, silicon carbide, amorphous silicon, silicon oxynitride and diamondlike carbon; and

making the nozzle in the second layer.

4. (original) The method of claim 3 wherein the first layer of dielectric material and the second layer of dielectric material is selected to be the same material.

5. (currently amended) A method of making a part of a droplet plate, which part mounts to a substrate that carries a heat transducer and defines both a firing chamber to surround the

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transducer and a nozzle through which liquid in the chamber may pass from the chamber; the method comprising the steps of:

forming the part from a first dielectric material by depositing a first layer of the dielectric material, ~~wherein the first dielectric material comprises silicon dioxide;~~

shaping the firing chamber in the first layer; then

depositing a second layer of the first dielectric material; and

making the nozzle in the second layer.

6. (currently amended) ~~A method of making a part of a droplet plate, which part mounts to a substrate that carries a heat transducer and defines both a firing chamber to surround the transducer and a nozzle through which liquid in the chamber may pass from the chamber; the method comprising the steps of:~~

~~forming the part from a first dielectric material by depositing a first layer of the dielectric material. The method of claim 5 wherein the first layer of dielectric material are selected from the group consisting of silicon dioxide, silicon nitride, silicon carbide, amorphous silicon, silicon oxynitride and diamondlike carbon;~~

~~shaping the firing chamber in the first layer; then~~

~~depositing a second layer of the first dielectric material; and~~

~~making the nozzle in the second layer.~~

7. (original) The method of claim 5 including the step of simultaneously exposing the first and second layers to one of an etchant or solvent.

8. (canceled).